

Considerations for resist outgas testing with EUV and hydrogen at NIST

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Resist Outgas TWG
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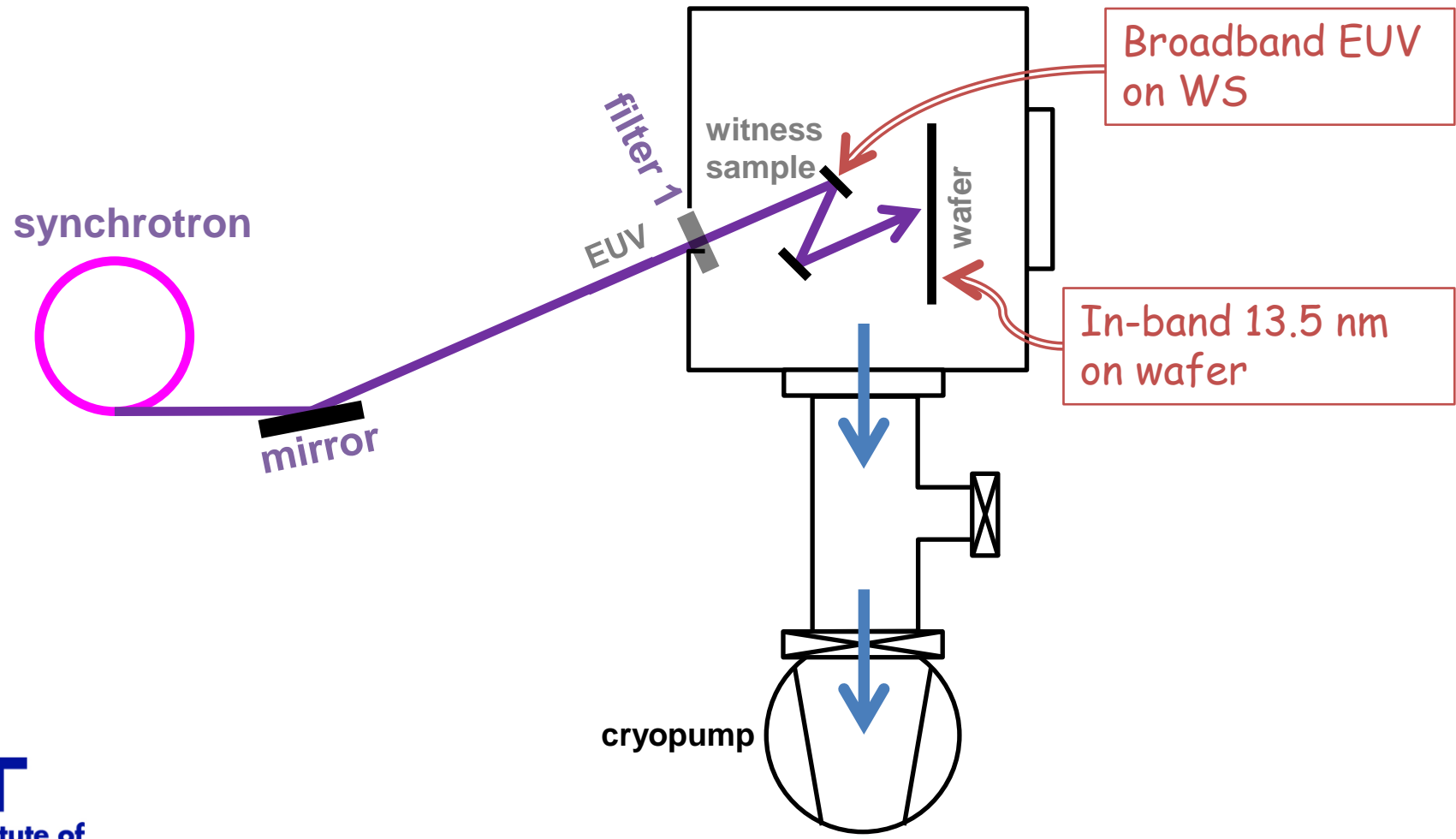
Existing outgas testing facility at NIST

Potential for outgas testing in hydrogen at NIST

Future plans

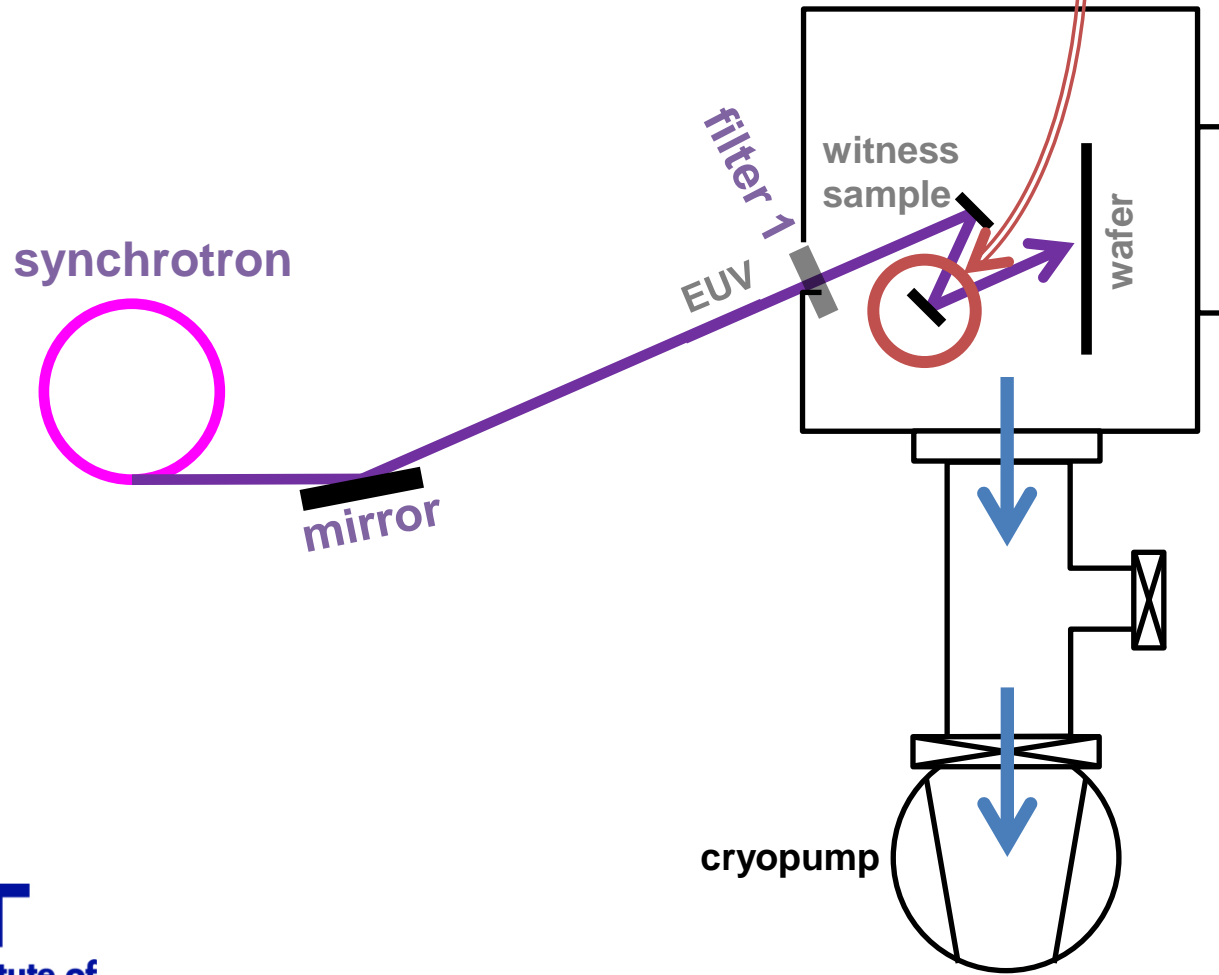
- **New commitments to NASA/NOAA**
- **Continued support of EUVL**

Existing outgas testing facility



Plan to increase power on wafer

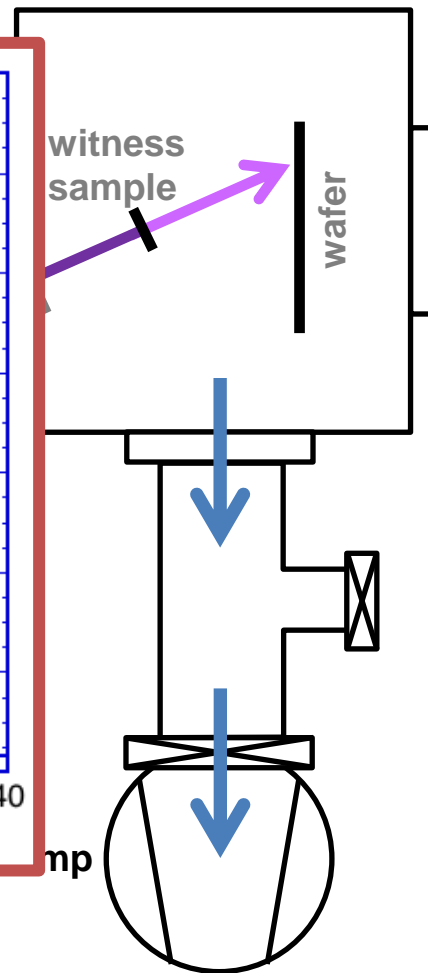
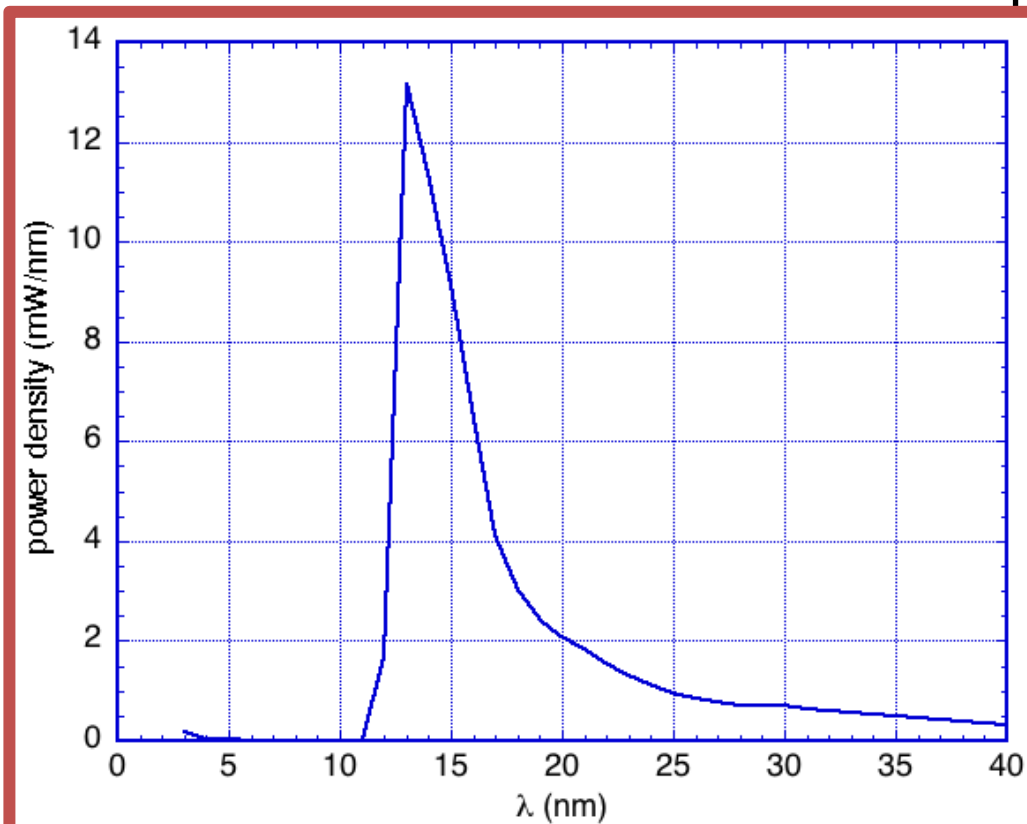
- Remove relay mirror



Plan to increase power on wafer

- Remove relay mirror
- WS intercepts central 40 % of beam

Broad-band EUV on WS and wafer

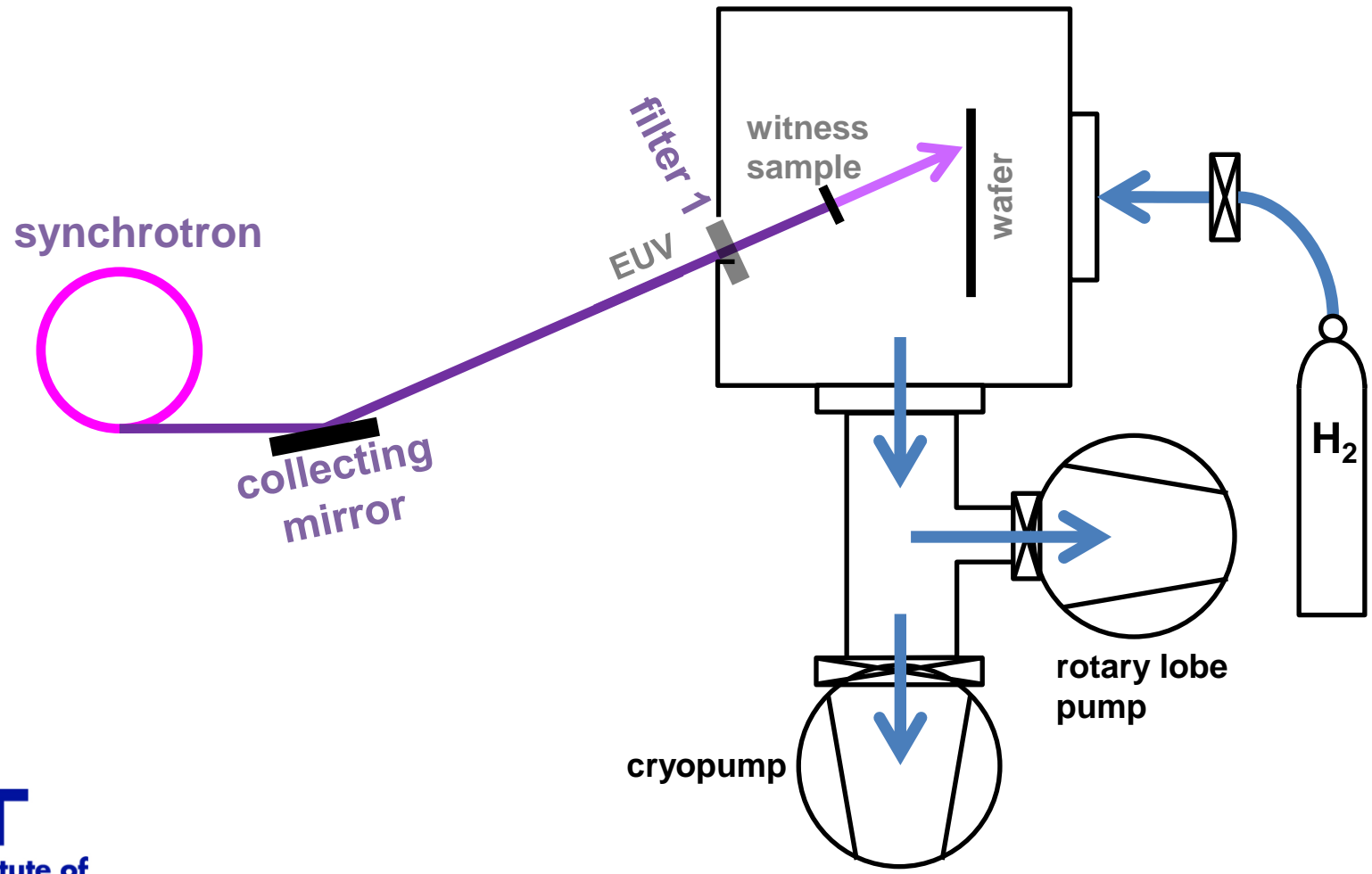


WS intensity:
(10-20) mW/mm²

Wafer power:
~40 mW

Plan to add hydrogen flow

Contaminating vapors diffuse through hydrogen atmosphere from wafer to witness sample.



Hydrogen pressure and flow rate

How much hydrogen?

pressure 1 mbar (750 mTorr, 100 Pa)
flow rate enough to remove outgassing of H₂O

Minimum pumping speed to keep up with H₂O outgassing

$$\dot{V}_{\text{pumpMin}} = \frac{Q_{\text{water}}}{P_{\text{H}_2\text{O}}} = \frac{(6 \times 10^{-7} \text{ mbar L s}^{-1})}{(1.0 \times 10^{-7} \text{ mbar})} = 6 \text{ L s}^{-1}$$

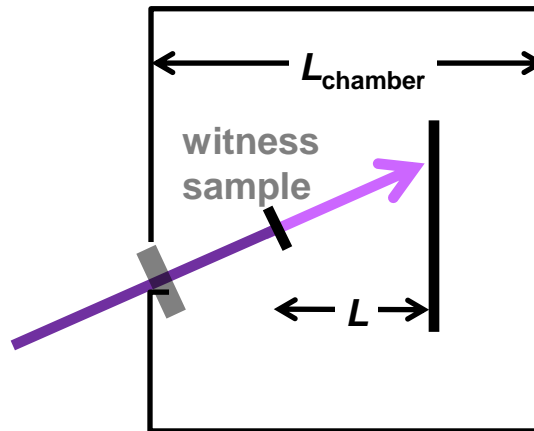
Corresponding flow rate

$$Q_{\text{H}_2\text{min}} = P \dot{V}_{\text{pumpMin}} = 6 \text{ mbar L s}^{-1} = 360 \text{ sccm}$$

Gas flow vs diffusion

Q: How much time is needed for outgas species to diffuse to the witness sample?

A: 0.03 s



$$t_D \equiv \frac{L^2}{D} = 0.03 \text{ s}$$

Q: How much time is needed for the H_2 flow to sweep out the volume L^3 ?

A: 0.8 s

$$t_{\text{flow}} \approx \left(\frac{L}{L_{\text{chamber}}} \right) \frac{V_{\text{chamber}}}{\dot{V}_{\text{pump}}} \approx \left(\frac{0.042 \text{ m}}{0.5 \text{ m}} \right) \frac{(56 \text{ L})}{(6 \text{ L s}^{-1})} = 0.8 \text{ s} \gg t_D$$

Outgas molecules will reach WS before being swept away

Protecting the NIST synchrotron (SURF III) from hydrogen

Risks

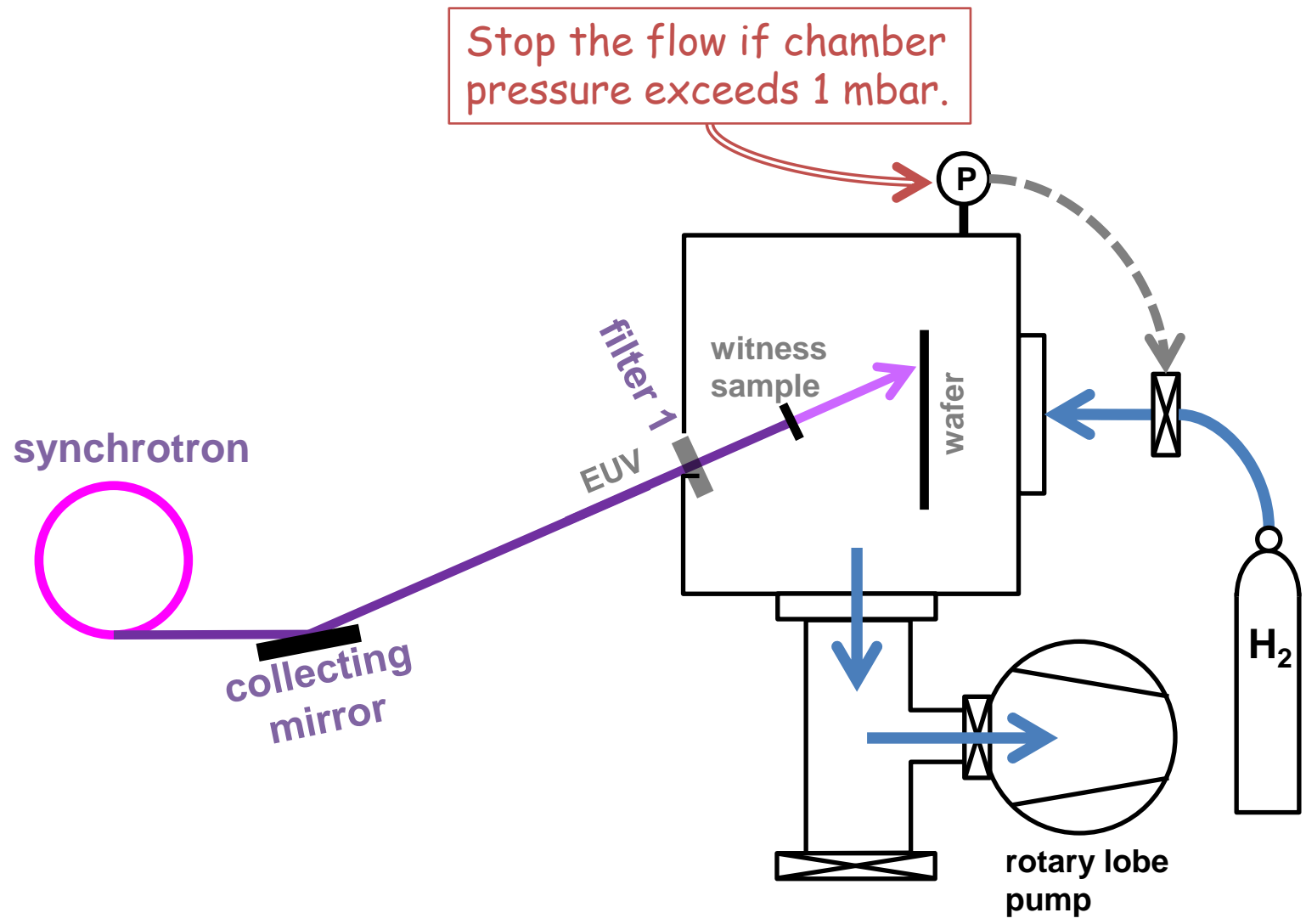
- A large, one-time dose of H₂ could permanently degrade SURF ion pumps
- Ion pumps are integral to the storage ring so cannot be repaired/replaced

Consequences

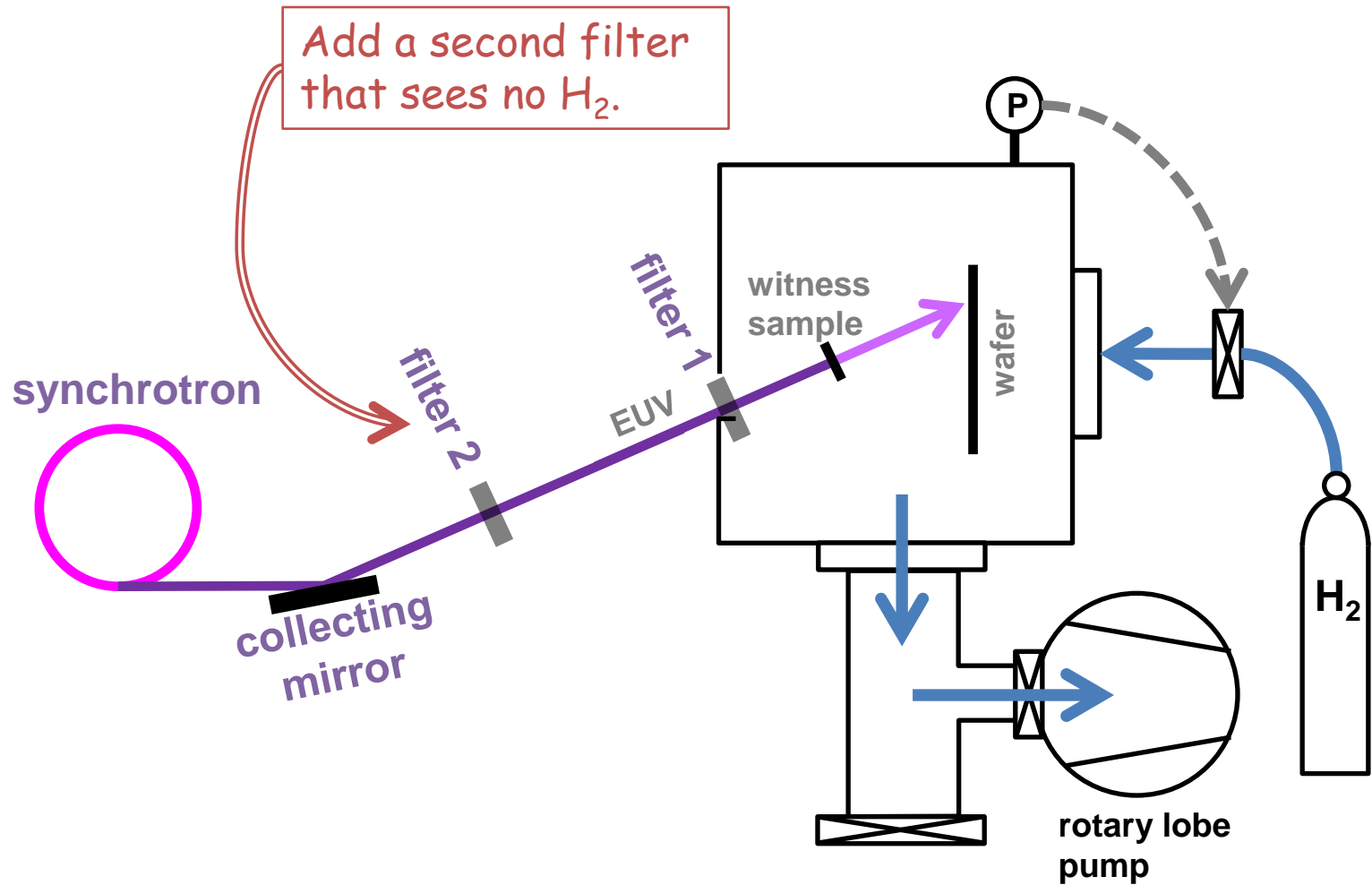
- Damaged ion pumps = **new synchrotron!**

SURF must be protected against a burst of hydrogen.

Plan to protect the synchrotron

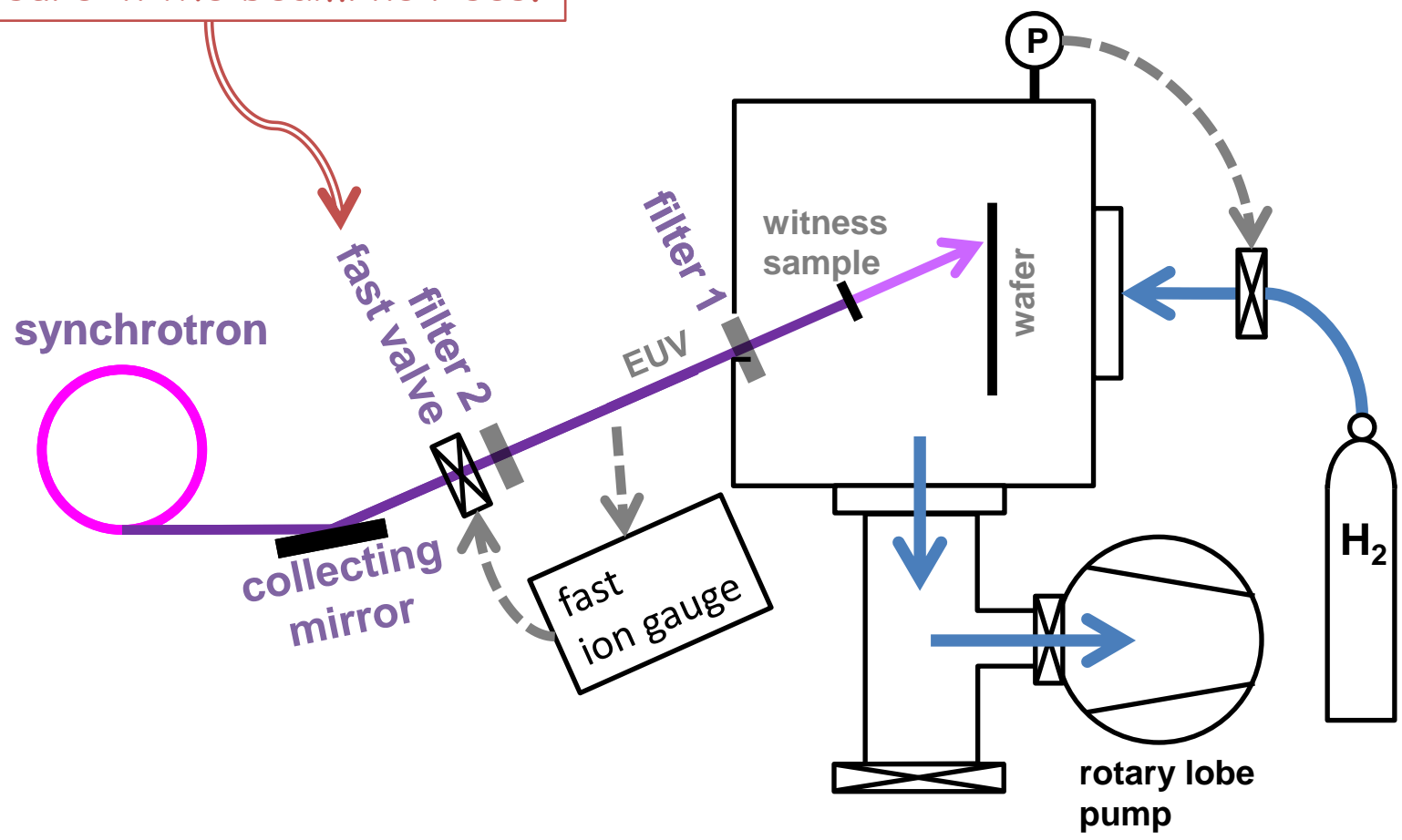


Plan to protect the synchrotron



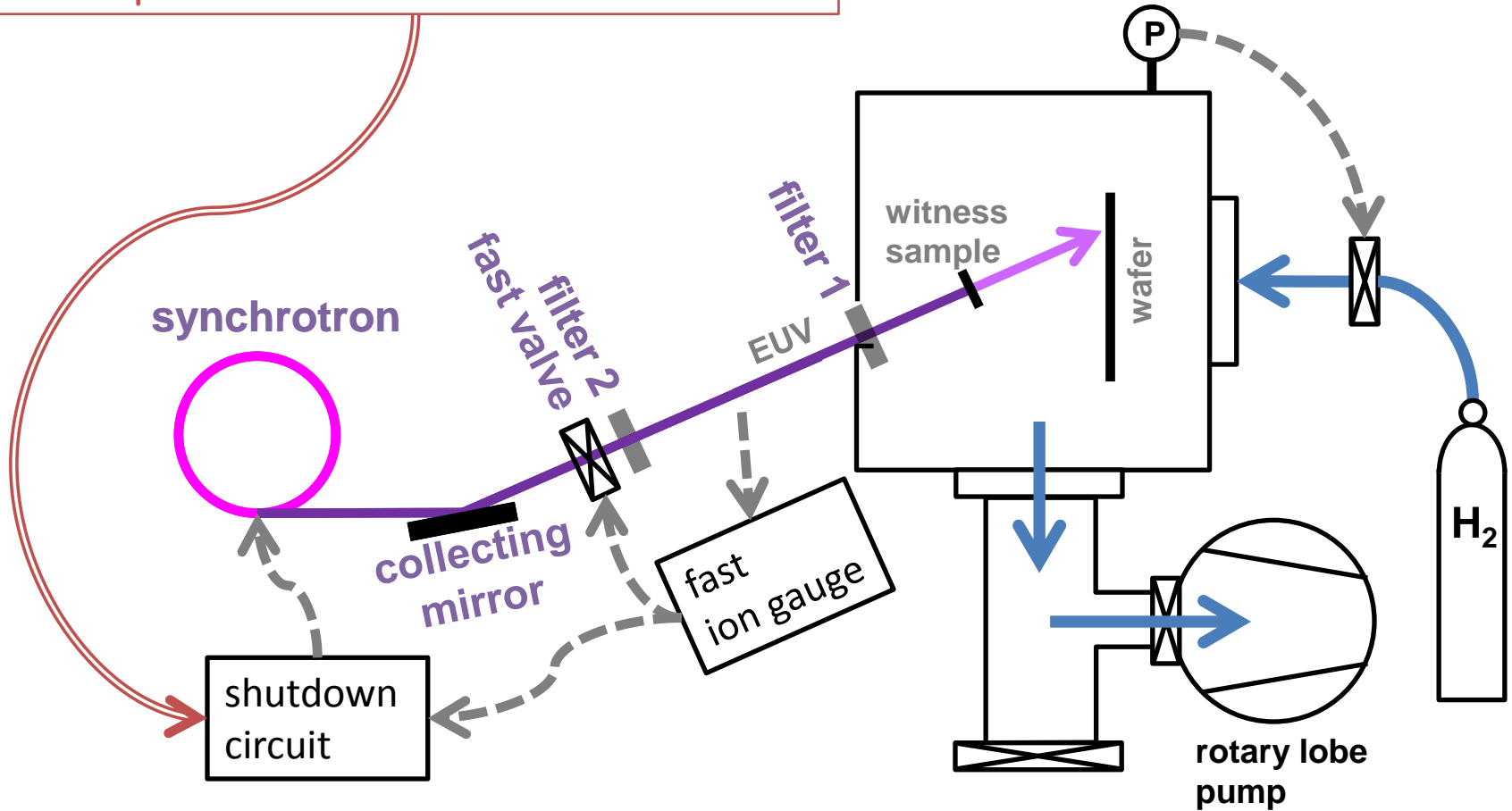
Plan to protect the synchrotron

Shut the fast valve (<10 ms)
if pressure in the beamline rises.



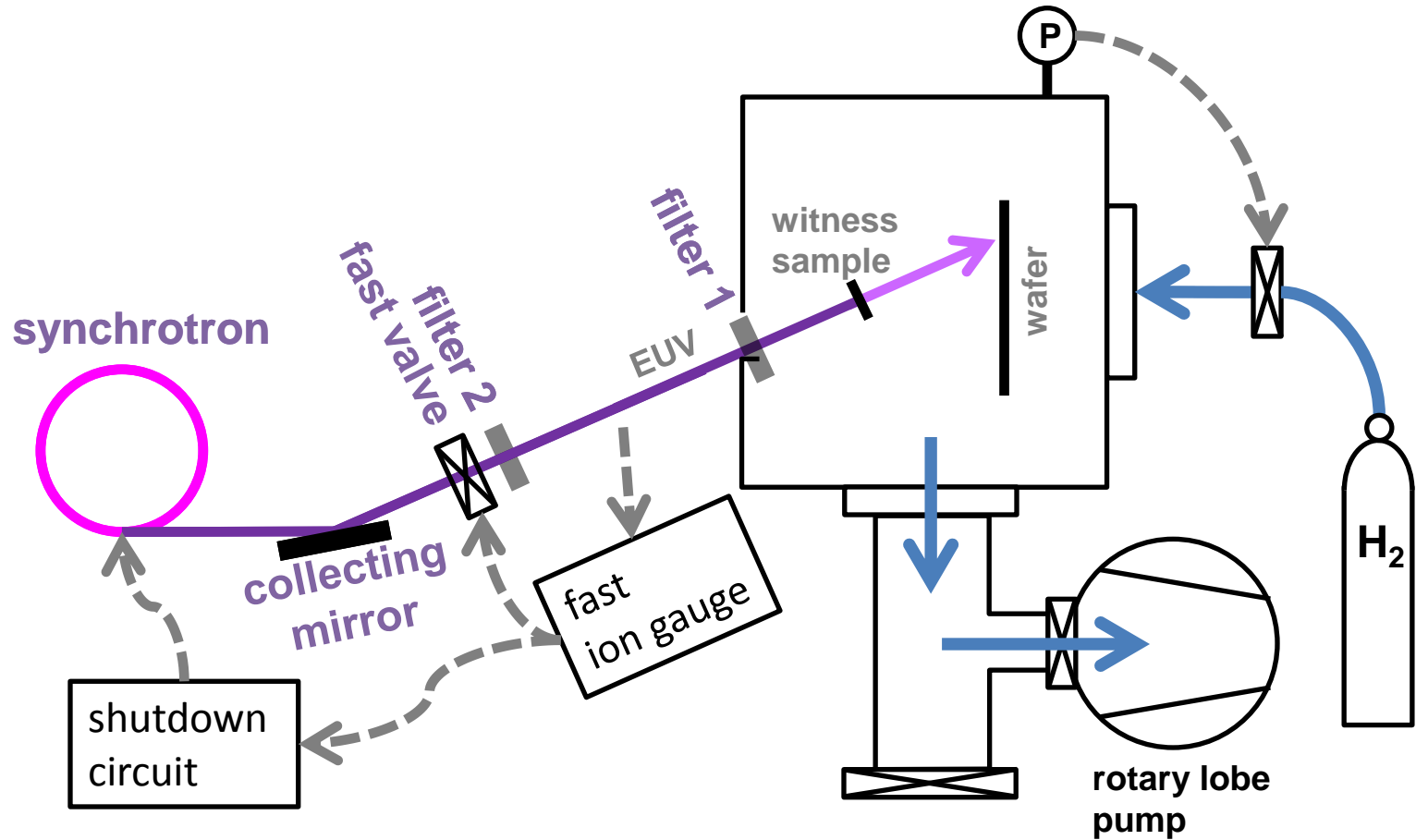
Plan to protect the synchrotron

Stop the synchrotron's ion pumps if pressure in the beamline rises.



Plan to protect the synchrotron

Significant capital investment for H₂ upgrade



Summary: proposed H₂ outgas testing facility

Hydrogen atmosphere

- Max pressure: 1 mbar
- Flow rate: 360 sccm

Average witness sample intensity

- (10-20) mW/mm²

Average power on wafer

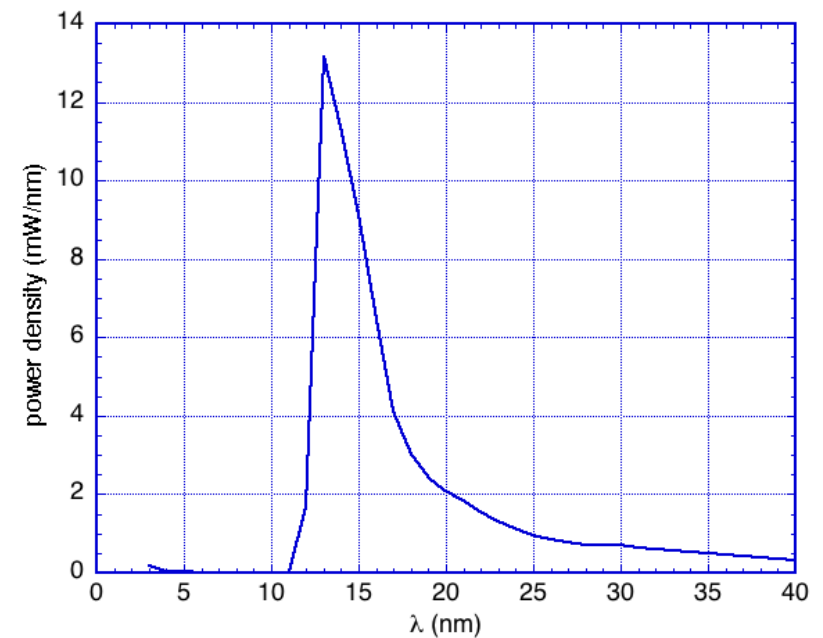
- ~40 mW

Pulse structure of EUV

- Rep rate: 114 MHz
- Pulse duration 1 ns
- Duty factor 10 %

Broad-band EUV on

- witness sample
- AND wafer



Substantial support from NOAA/NASA to study degradation of solar-observing satellite instruments

Requires commitment to one of following options by April 2016

Current plan: modify outgas testing beamline for NOAA program

- Standard outgas tests may require extra time
- Upgrade to H₂ configuration would require greater support and time

Optional plan: perform NOAA work on new beamline

- Continued availability of standard resist-outgas testing
- Easier upgrade of outgas beamline to H₂ configuration
- Substantially increases cost/time for NOAA work